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LMC:ejv 02/17/10 23-69853-01 E-1861

<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>	Attorney Docket Number	23-69853-01
	Application Number	10/727,062
	Filing Date	December 2, 2003
	First Named Inventor	John G. DeSteele
	Art Unit	1795
	Examiner Name	Jeffrey Thomas Barton

**U.S. PATENT DOCUMENTS**

Copies of U.S. Patent documents do not need to be provided, unless requested by the Patent and Trademark Office. For patents, provide the patent number and the issue date. For published U.S. applications, provide the publication number and the publication date. For unpublished pending patent applications, provide the application number and the filing date and submit a copy.

Examiner's Initials*	Cite No. (optional)	Number	Date	Name of Applicant or Patentee
		3,900,603	8/1975	Rittmayer et al.
		4,249,121	2/1981	Dahlberg
		5,883,563	3/1999	Horio et al.
		6,046,398	4/2000	Foote et al.
		2003/0089391	5/2003	Fukudome et al.

**FOREIGN PATENT DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	Country	Number	Date	Name of Applicant or Patentee
		EPC	0034538	8/1981	
		DE	6900274	8/1970	
		DE	2124465	11/1972	
		DE	2457586	6/1975	
		JP	43-25391	11/1968	
		JP	7-7186	1/1995	
		JP	7-335943	12/1995	
		JP	10-51037	2/1998	
		JP	2003-92432	3/2003	

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		CH	677421	5/1991	
		WIPO	99/54941	10/1999	

**OTHER DOCUMENTS**

Examiner's Initials*	Cite No. (optional)	
		Final Office action from the U.S. Patent and Trademark Office in U.S. Patent Application No. 10/581,281, dated December 16, 2009.
		Kim, et al., "Effects of a Reduction Treatment and Te Doping Properties of $(\text{Bi}_{1-x}\text{Sb}_x)_2\text{Te}_3$ Fabricated by Mechanical Alloying," <i>16th International Conference on Thermoelectrics</i> , pp. 127-130 (1997).
		Notification of Reasons for Refusal from the Japanese Patent Office for Japanese Patent Application No. 2006-542773, dated January 20, 2010 (with translation).
		Yamashita, O. et al., "Bismuth telluride compounds with high thermoelectric figures of merit," <i>Journal of Applied Physics</i> , Vol. 93, No. 1, pp. 368-374 (January 1, 2003).

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